

The KEK-All Ion Accelerator (KEK-AIA)

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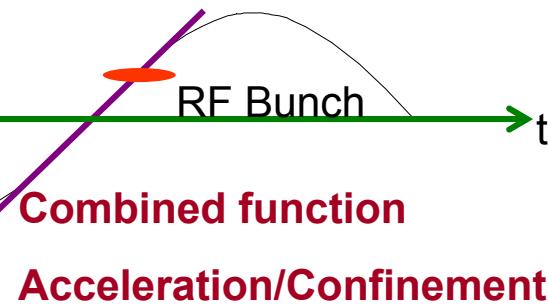
- Introduction of Induction synchrotron concept and its POP experiment
- Motivation for AIA
- KEK-PS Booster modification for AIA
- Acceleration scenario in the AIA
- New cell – 2 μ sec long pulse cell
- Gate control system
- Summary



Induction Synchrotron Concept

RF Synchrotron

RF Voltage
Voltage with gradient



Induction Synchrotron

Pulse voltage  t

For Acceleration

Separate function

For Confinement

Induction cell for confinement

Induction cell for acceleration

Accelerator Ring

for proton and other ions

Proton or Ion
bunch

Super-bunch

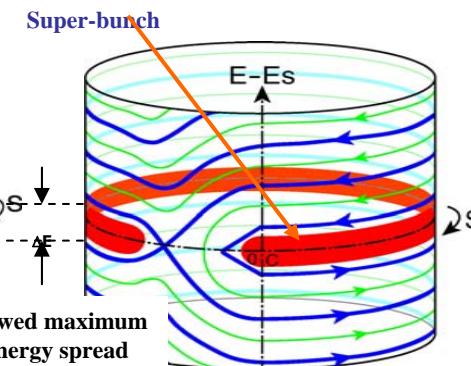
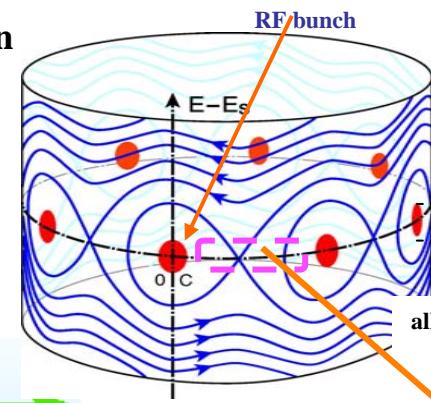
time

V_{barri}

Induction cell for acceleration

V_{acc}

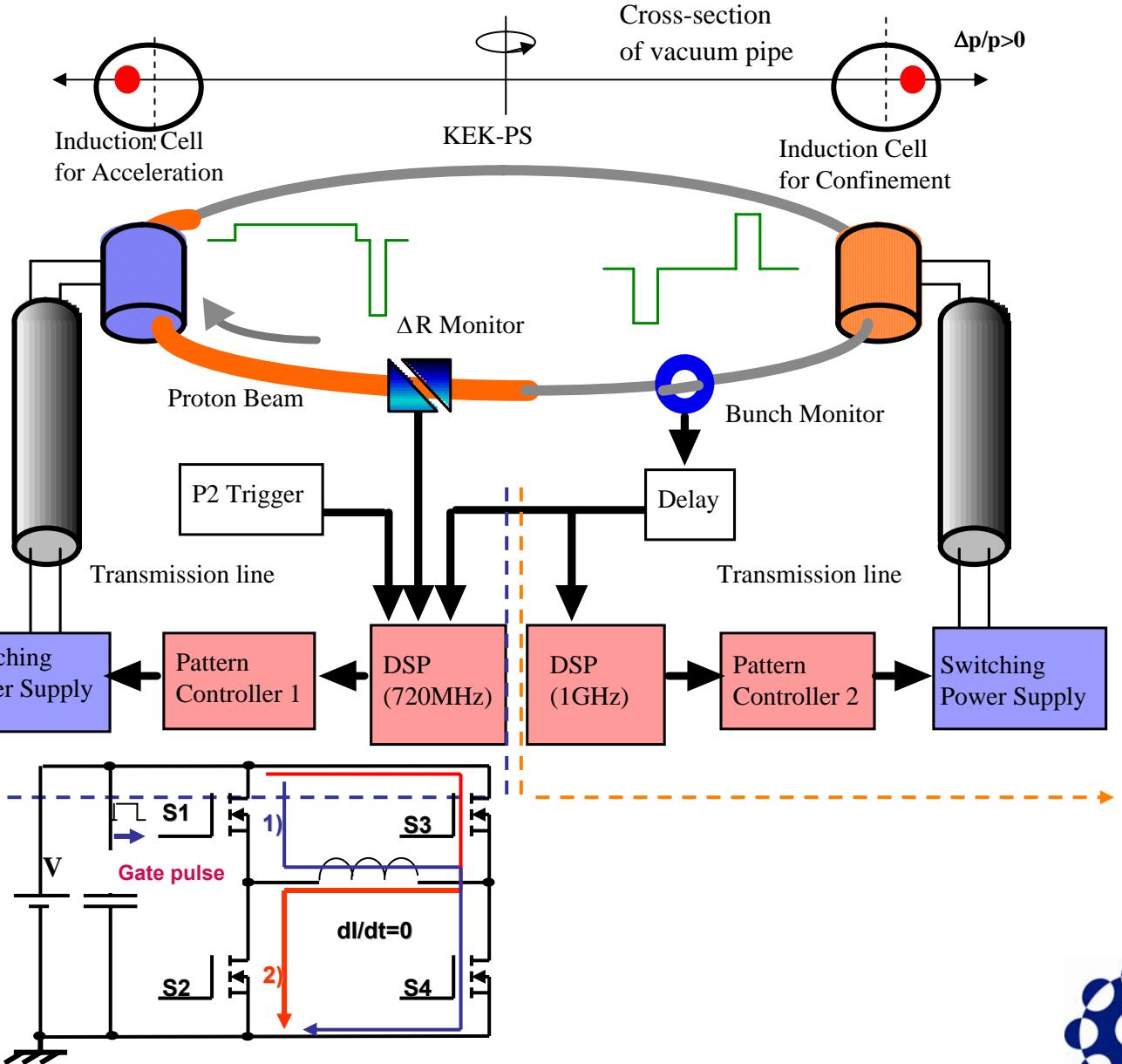
Difference between RF Synchrotron and Induction Synchrotron seen in Phase-space



This space is not available for acceleration.



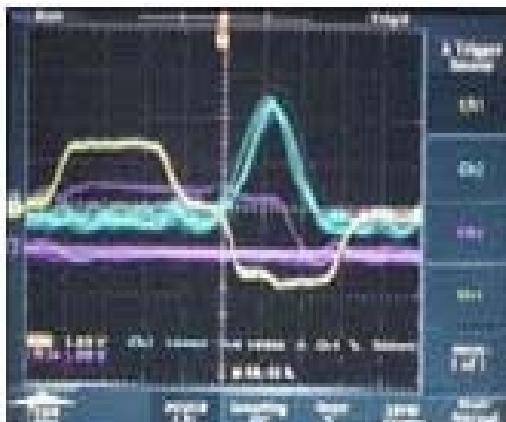
Induction acceleration system and controls for POP



P2 (just start of accel.)



P2+400 msec



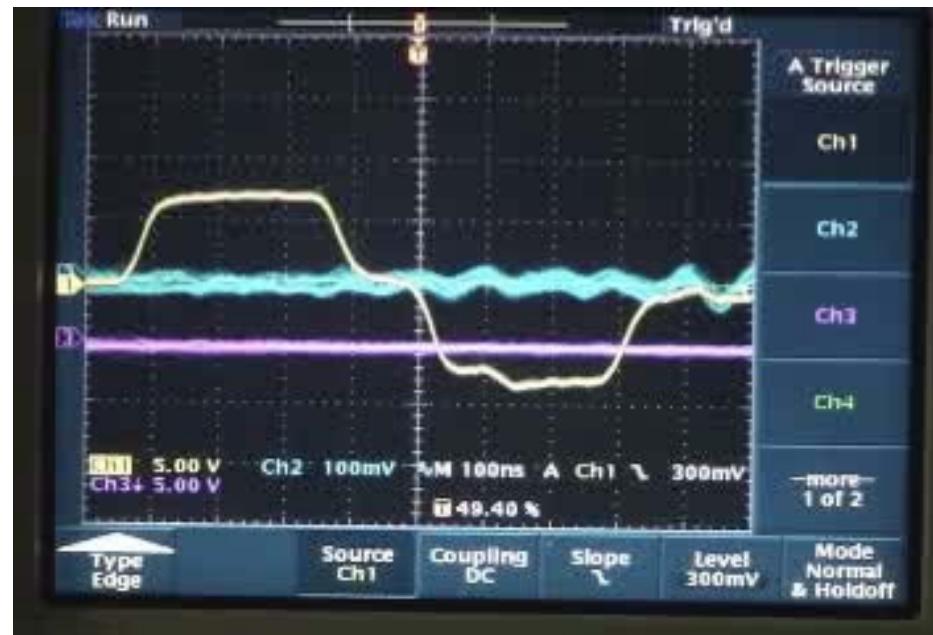
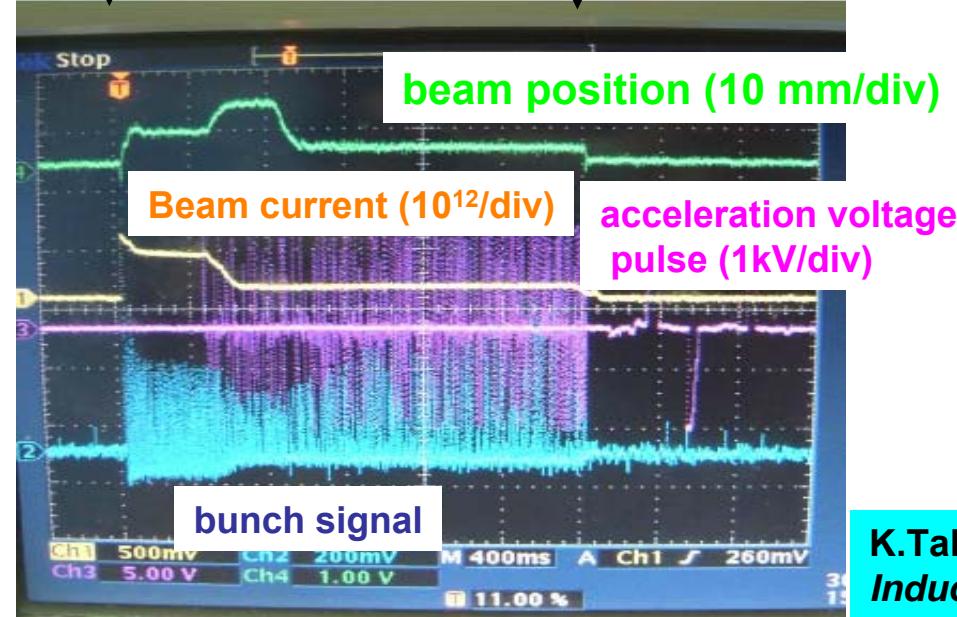
near end of accel. (6GeV)



T.Dixit et.al. "Adiabatic damping of bunch length in Induction Synchrotron" NIM-A 582 (2007)

Movie of the POP experiment

Injection (500MeV) Start of acceleration End of acceleration
↓ ↓ ↓
End of acceleration (6GeV)



K.Takayama et al., "Experimental Demonstration of the Induction Synchrotron", Phys. Rev. Lett. 98, 054801 (2007)

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- Acceleration scenario in AIA
- New cell – 2 μ sec long pulse cell
- Gate control system
- Goal and time table

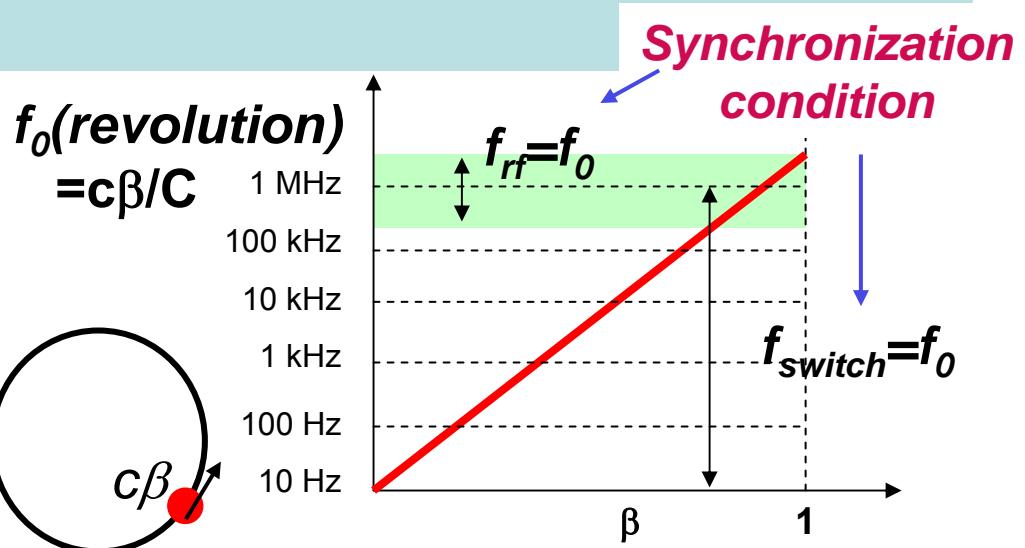


from the Induction Synchrotron to All-ion Accelerators

from the experimental demonstration of induction acceleration in the KEK-PS

- Stable performance of the switching power supply from ~0Hz to 1MHz
- Master trigger signal for the switching P.S. can be generated from a circulating beam signal

Allow to accelerate
even quite slow particles



A single circular strong-focusing machine can accelerate from proton to uranium,
maybe including **cluster ions**.



All-ion accelerators

almost injector-free
for a low intensity beam

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AIA Working Groups

Main Magnet/Orbit

*Low field operation
COD correction*

Source/ Injection group

ECR ion source

200 keV beam line

Electrostatic kicker

Extraction kicker

AIA

Monitor system

*Low current bunch
monitor*

*Low current ΔR
monitor*

Acceleration system

Acceleration scenario

New cell

Gate control system



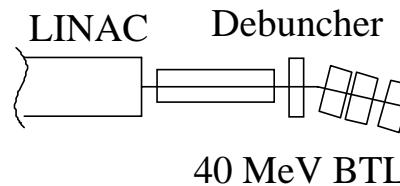


AIA using KEK PS-Booster

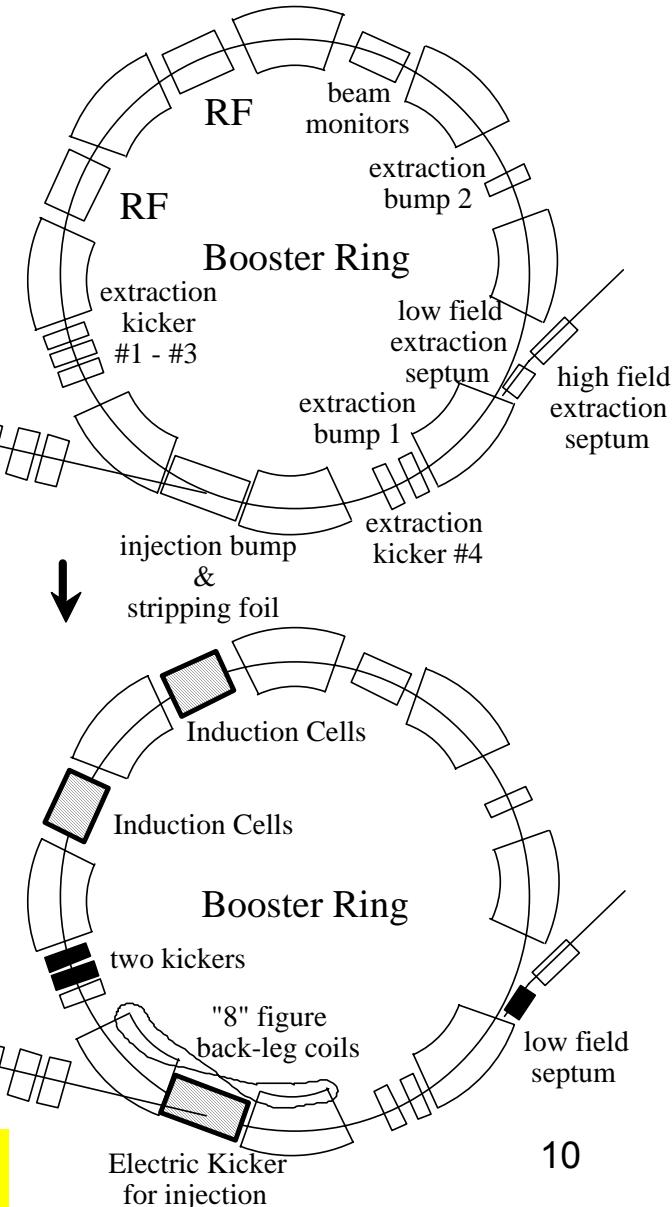
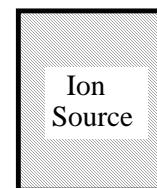
Parameters	Value
Magnetic flux, B_{\min}	0.02916 T
Magnetic flux, B_{\max}	0.8583 T
Frequency of magnet ramping	10 Hz
Bending radius, ρ	3.3 m
Circumference, C_0	37.71 m
Maximum acceleration voltage	3.24 kV

$^{40}\text{Argon}$

KEK 12GeV-PS
500 MeV Booster
Rapid Cycle Synchrotron

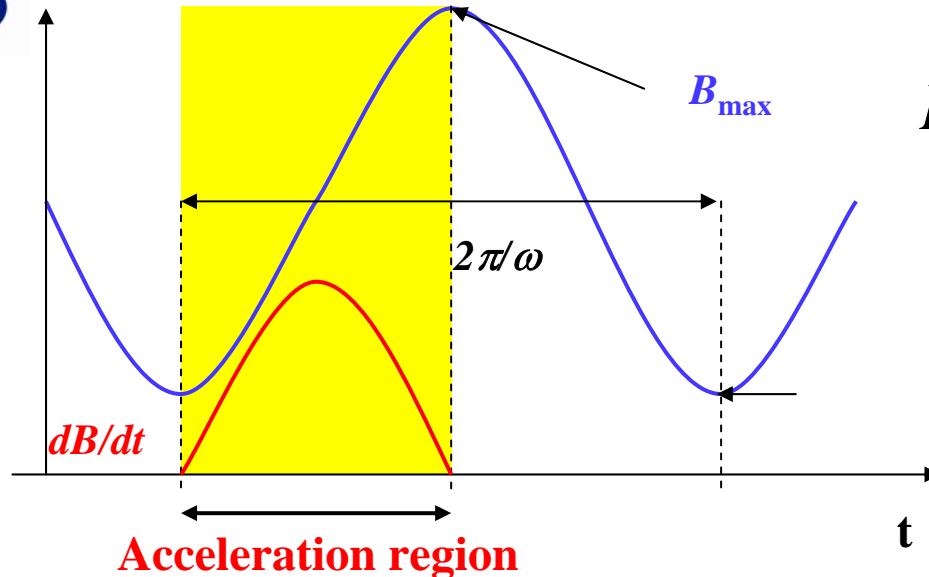


AIA
Induction Synchrotron





Booster Synchrotron –A Rapid cycle synchrotron



$$B(t) = B_{dc} - B_{ac} \cos \omega_{B_{ac}} t$$

$$V_{ac} = \rho C_0 \frac{dB(t)}{dt}$$

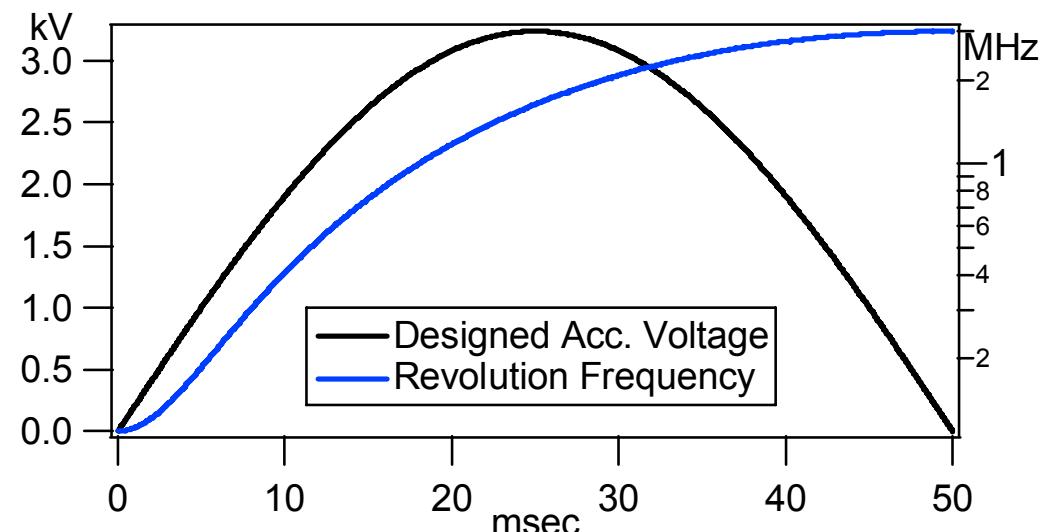
$$V_{ac} = 3.24 \text{ kV (peak)}$$

for 10 Hz operation

Acceleration voltage requirement
always transient from 0 V to peak
to 0 V

Solution - Pulse density control

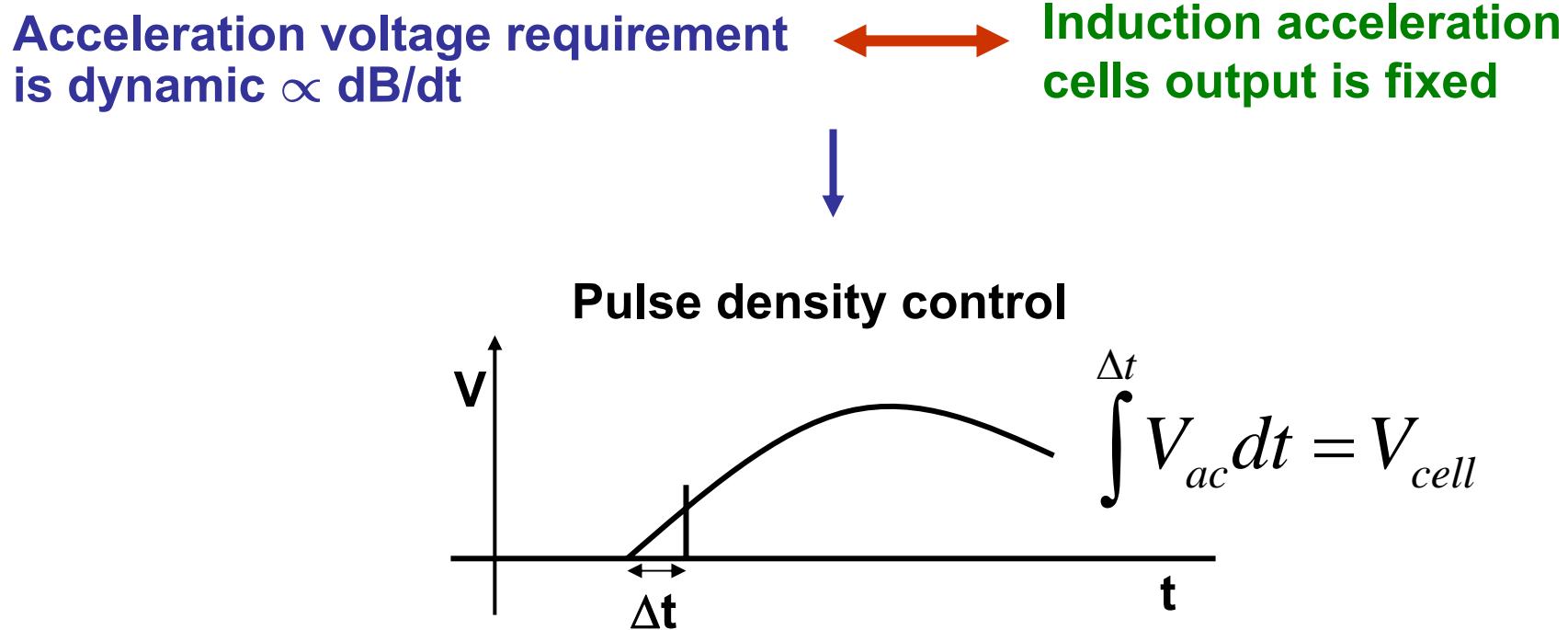
Near injection, revolution time is
large therefore longer flat
acceleration voltage pulse is
required





Pulse density control

- Trigger based system – acceleration voltage pulses can be controlled using trigger



Contents

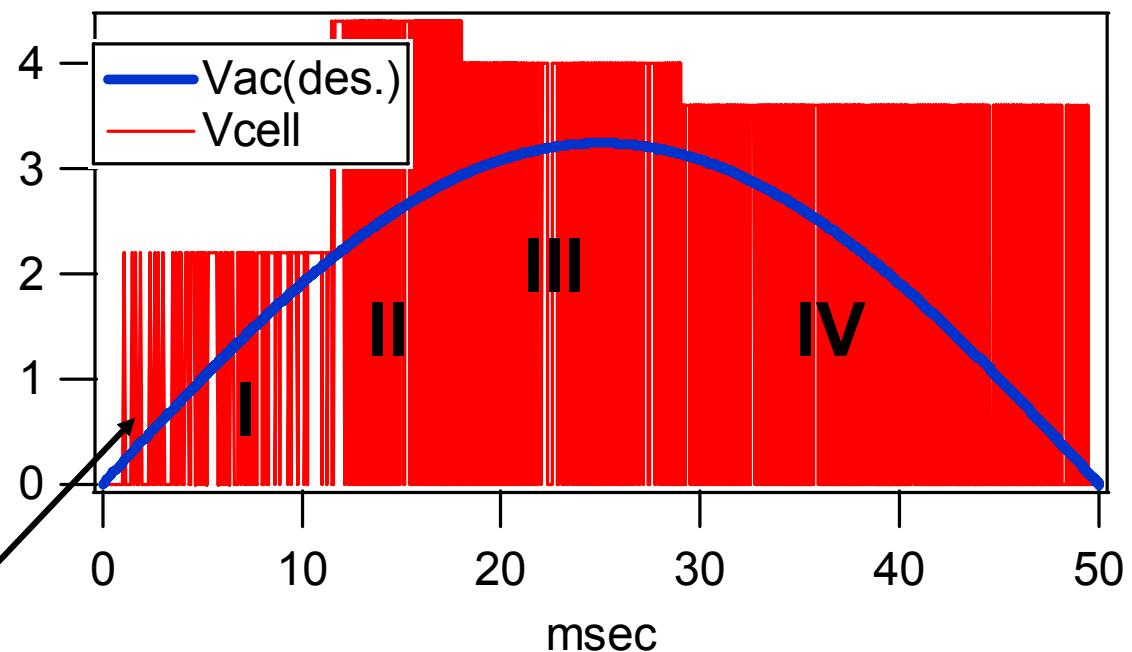
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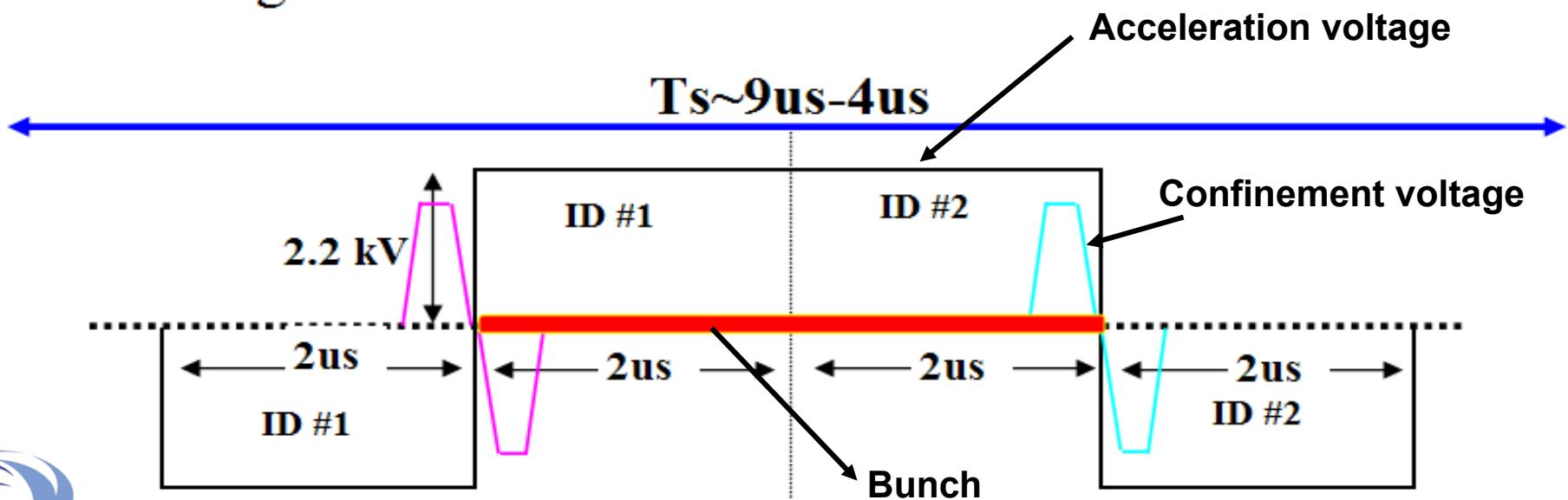
ACCELERATION SCHEME for AIA kV

Prerequisites

- 4 usec injected bunch
- 2.2 kV and 2 usec Acceleration voltage pulse
- 1.8 kV and 250nsec confinement voltage pulse

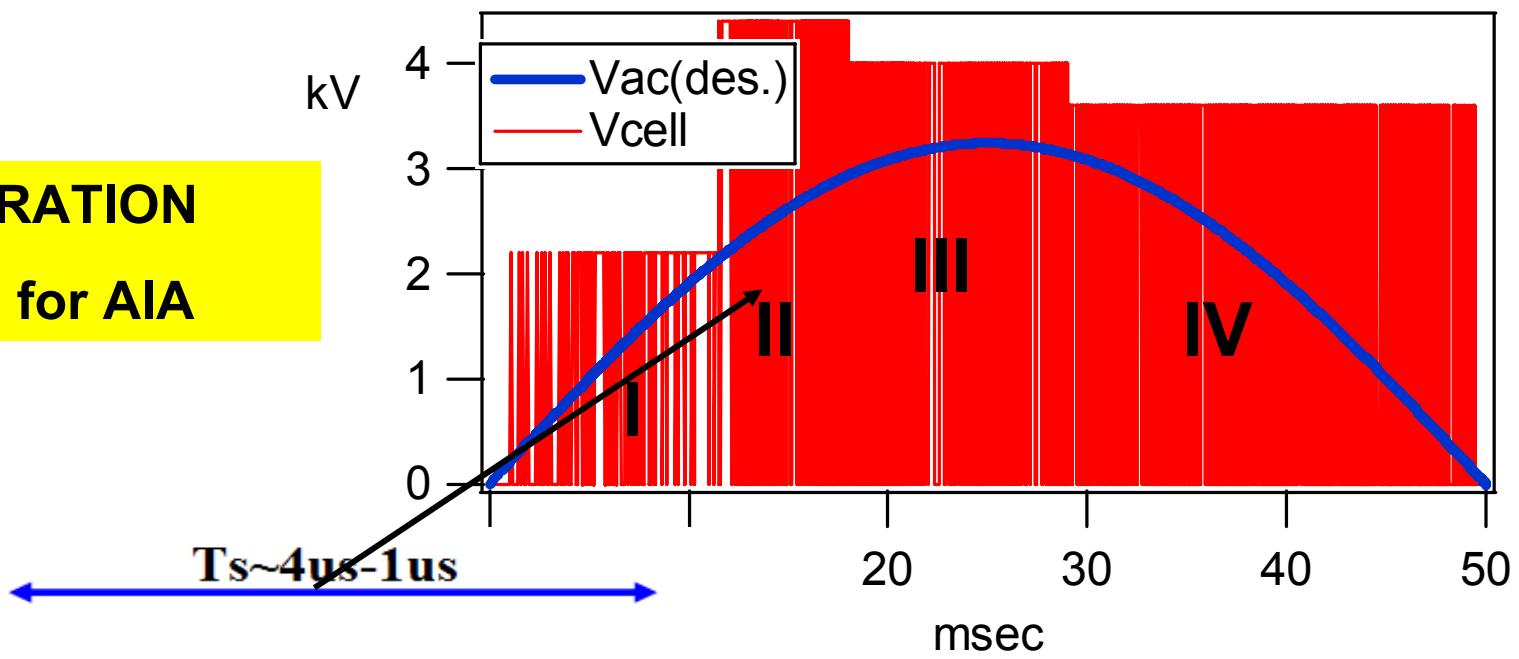


Stage 1.

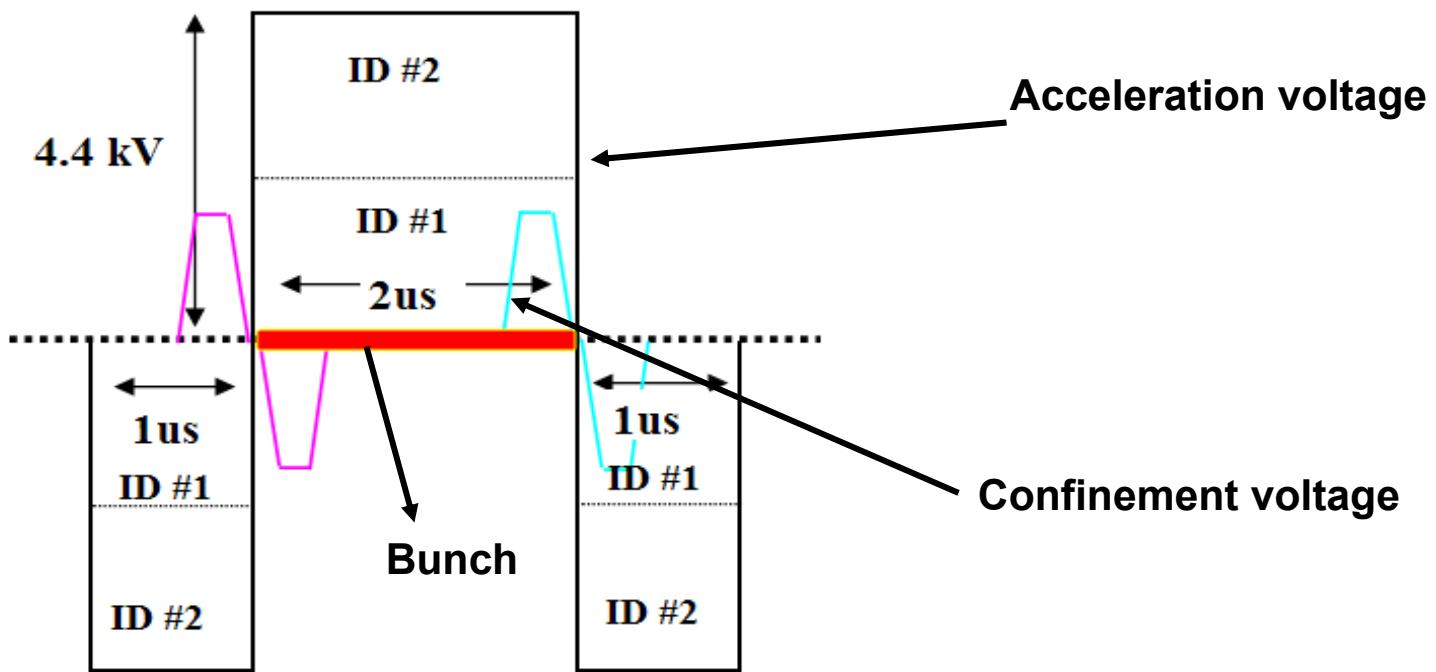




ACCELERATION SCHEME for AIA

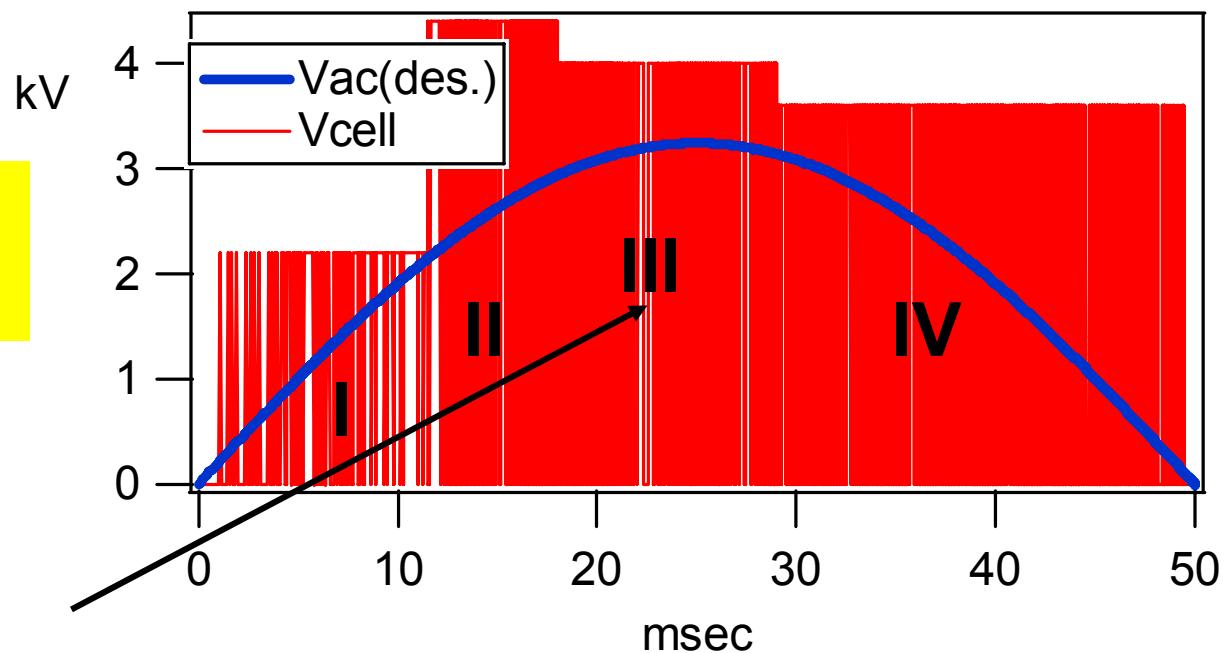


Stage 2.

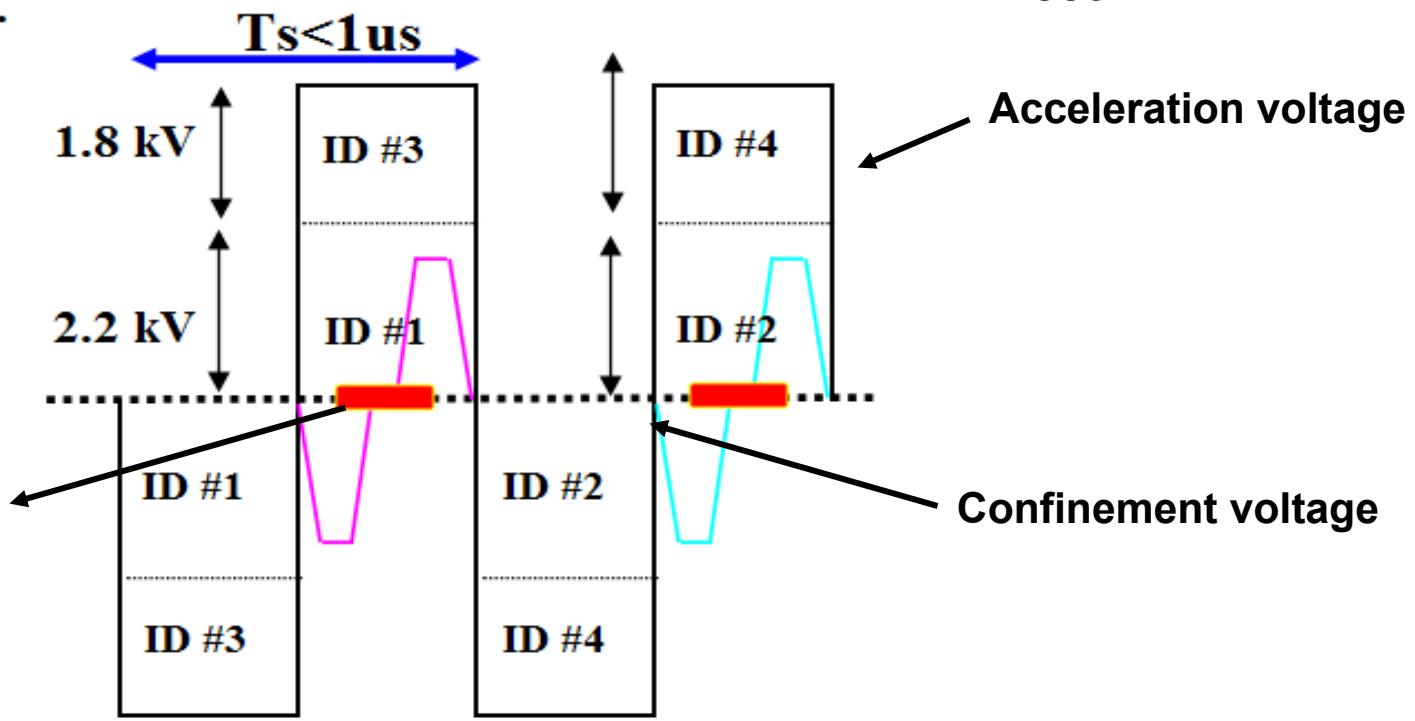




ACCELERATION SCHEME for AIA

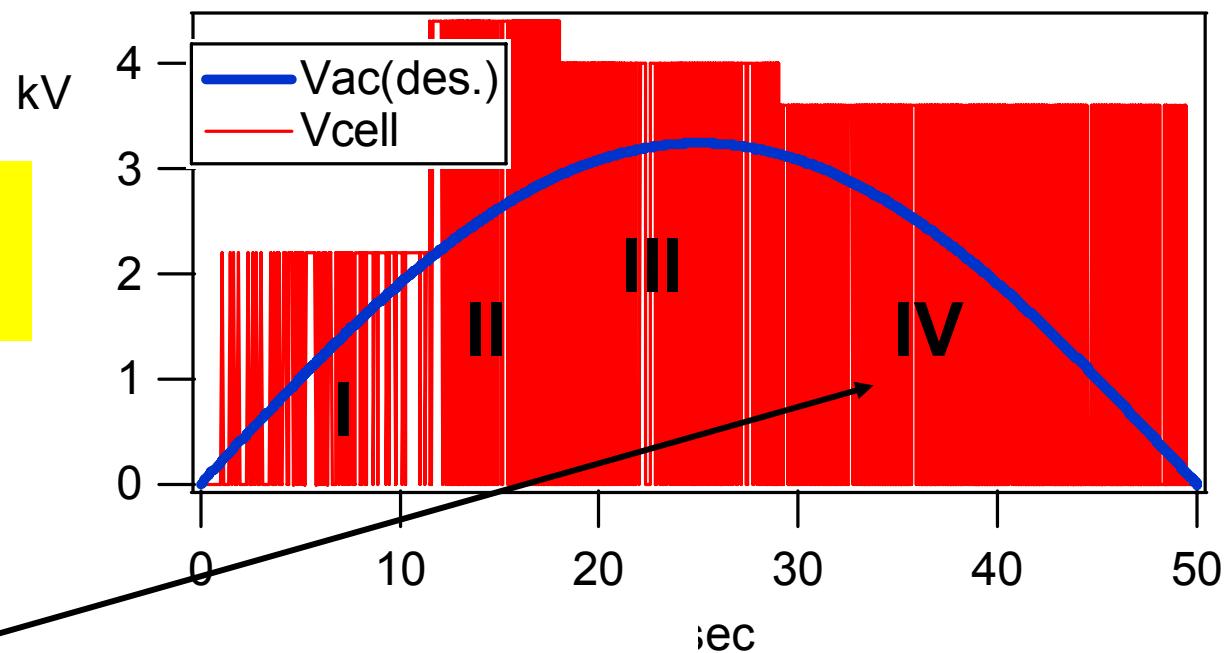


Stage 3.

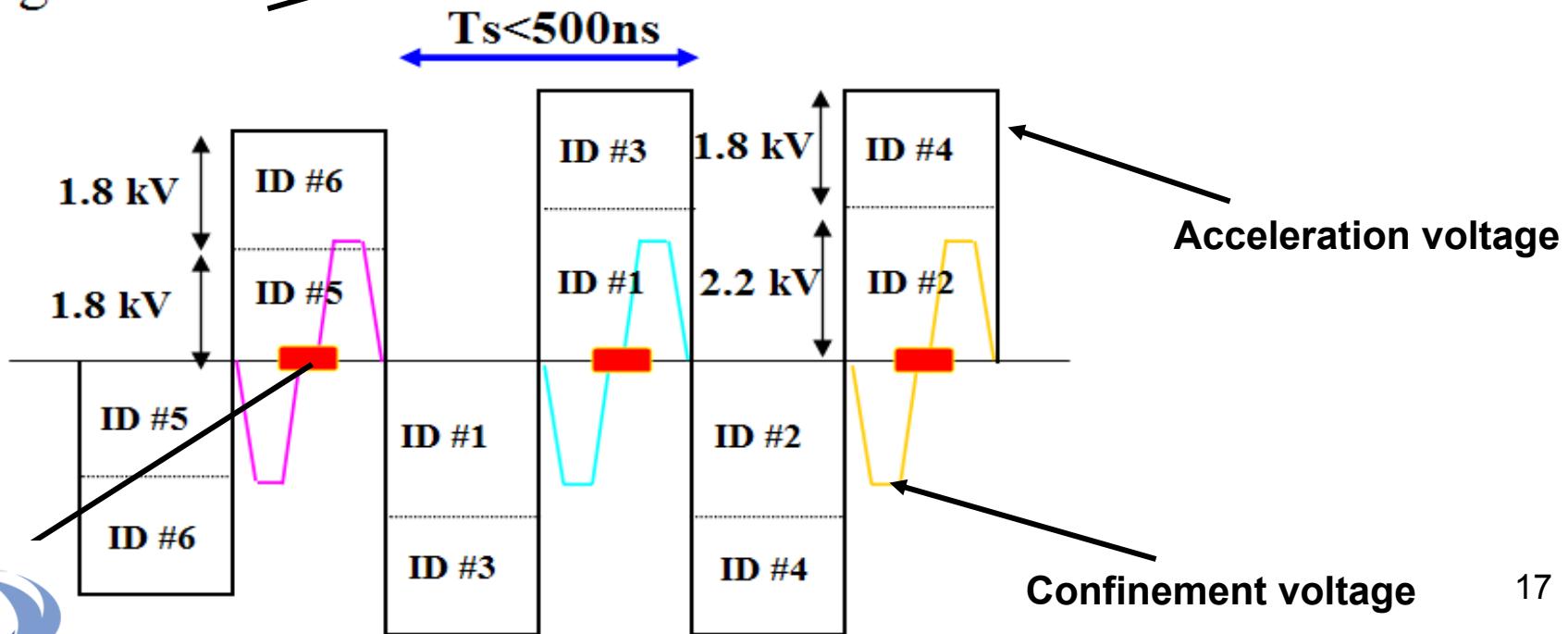




ACCELERATION SCHEME for AIA



Stage 4.



Simulation results



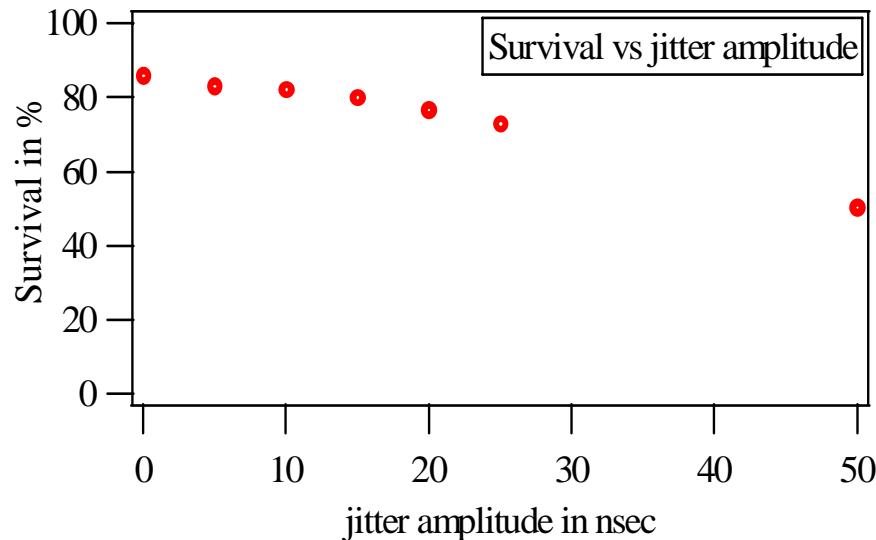
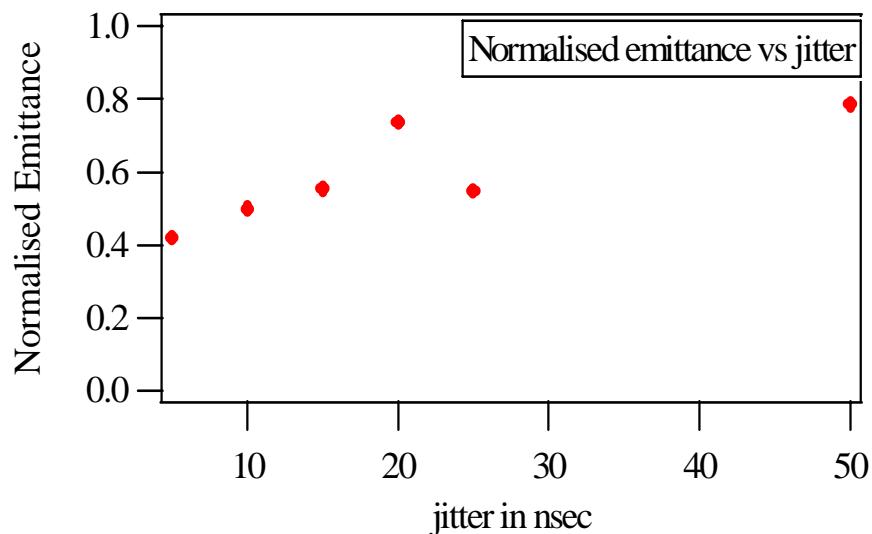
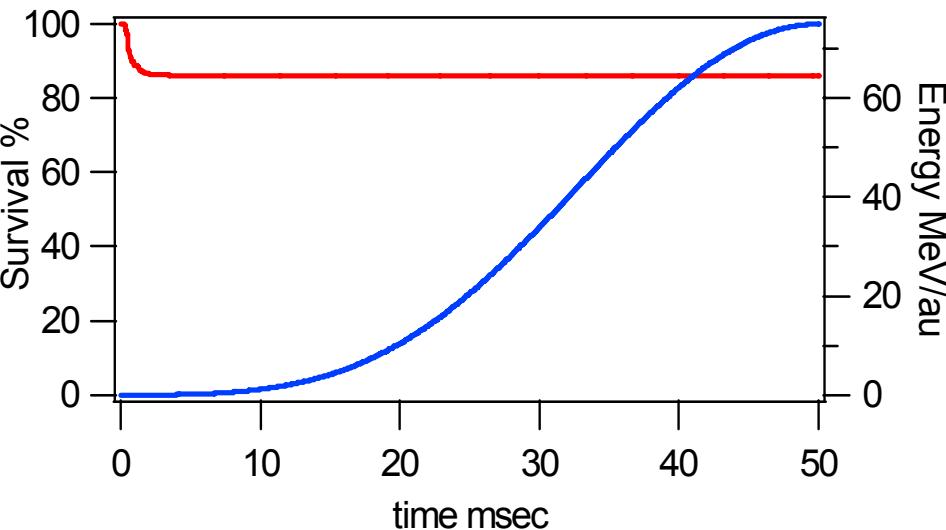
No. of particles – 10000

Initial beam $\Delta p/p - \pm 0.4\%$ (assumption)

Momentum aperture - $\pm 1\%$

Barrier voltage - 1.8 kV

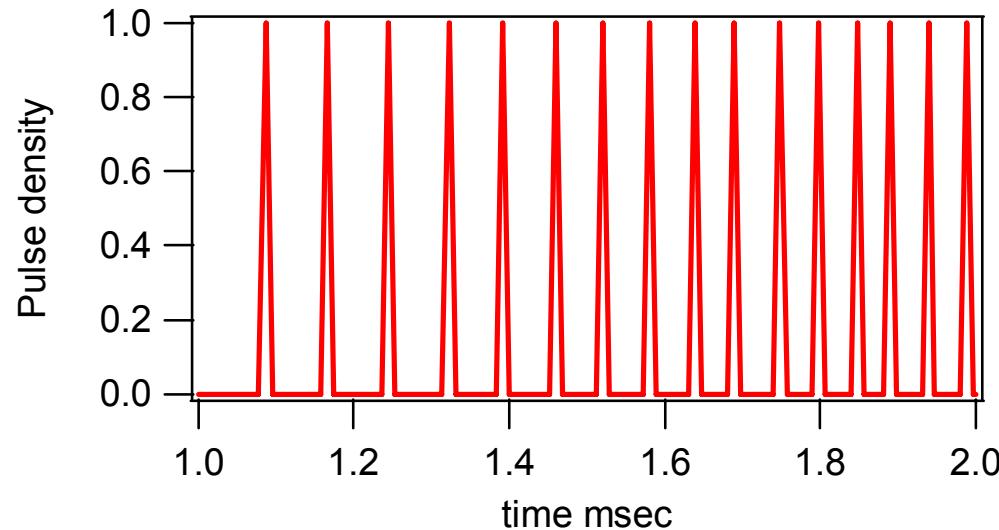
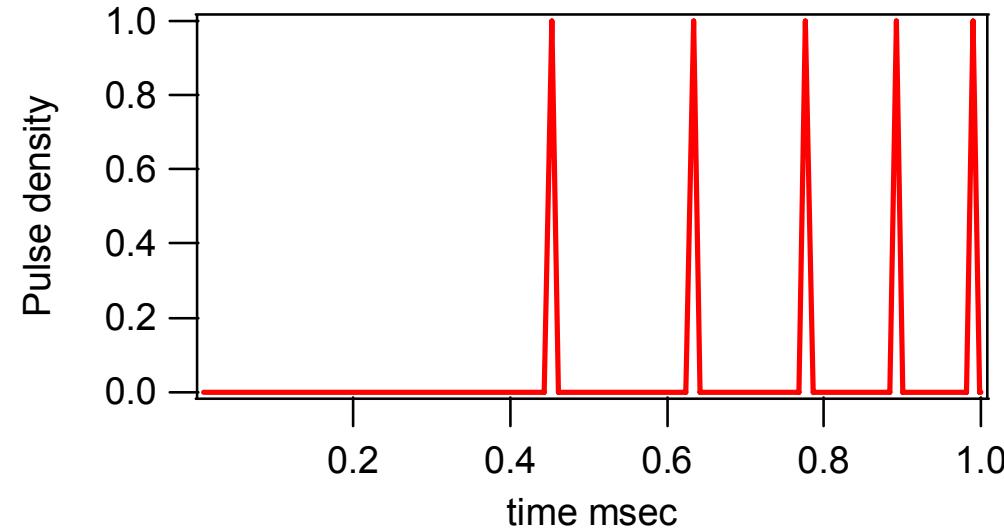
Beam survival & Energy gain Vs Time





Simulation results

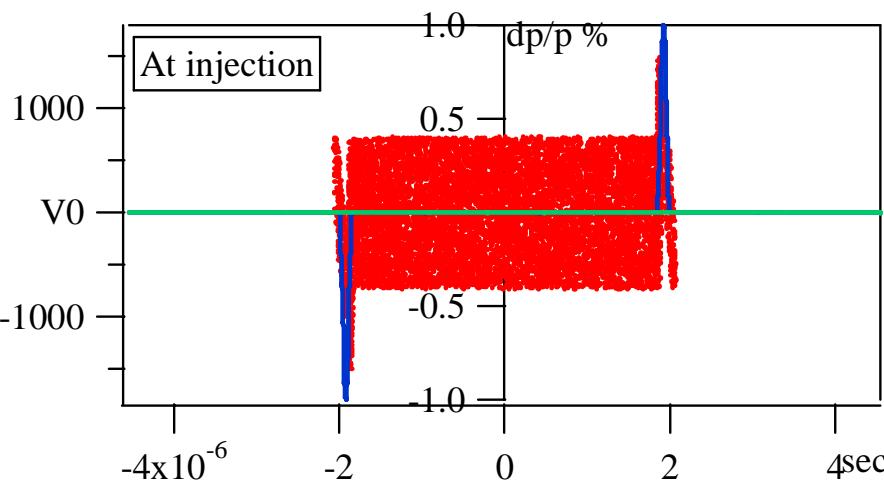
Pulse density Vs Time





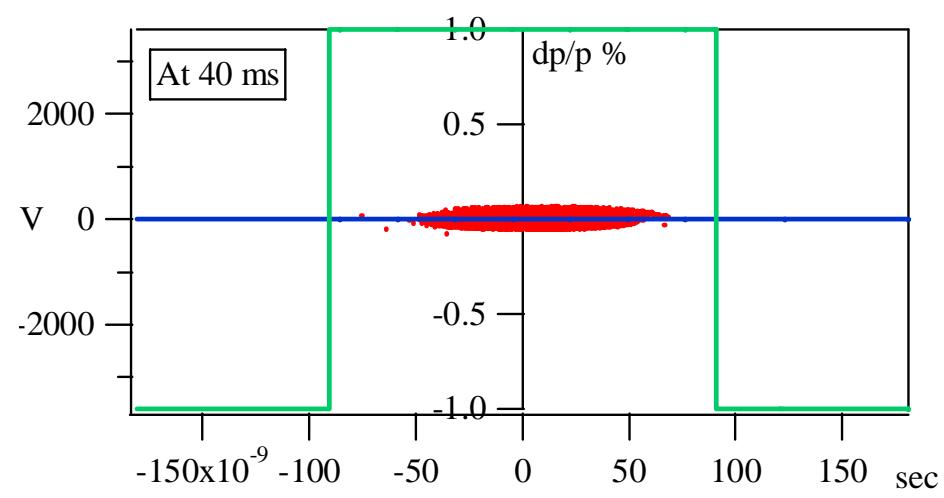
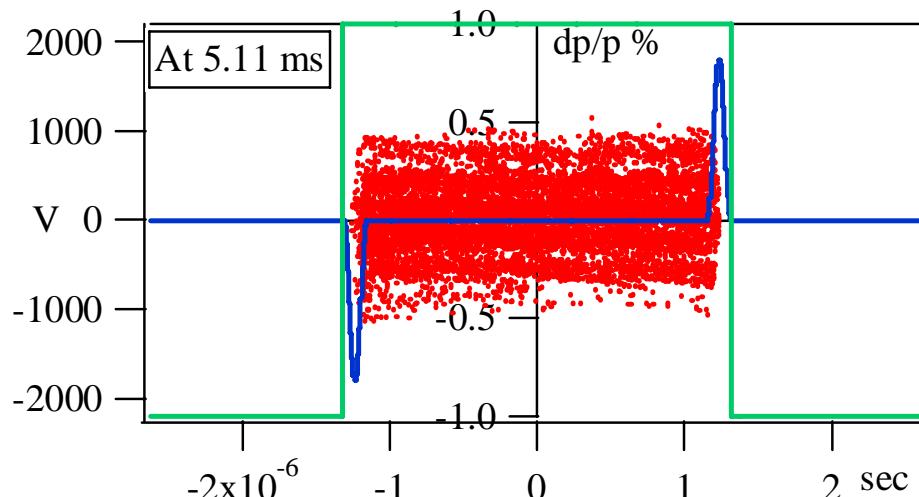
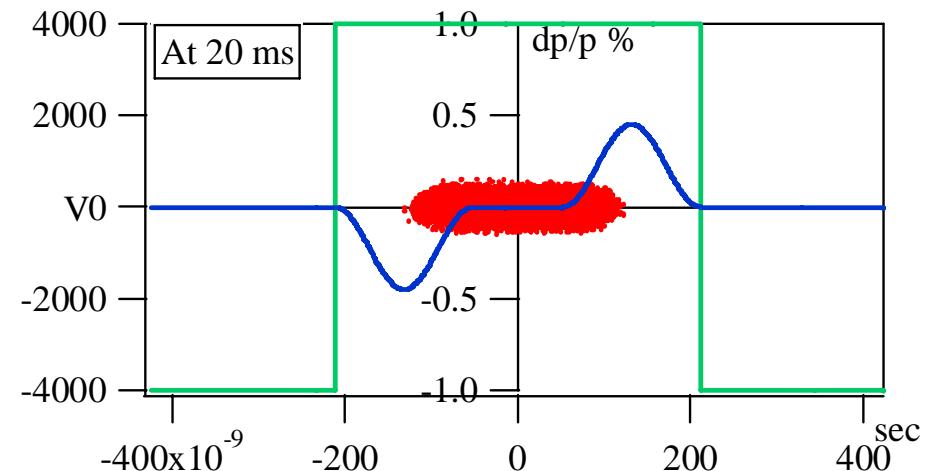
Argon Ion Longitudinal phase space plots

Blue- Barrier voltage pulse



Green-Acceleration voltage pulse

Red- Particles

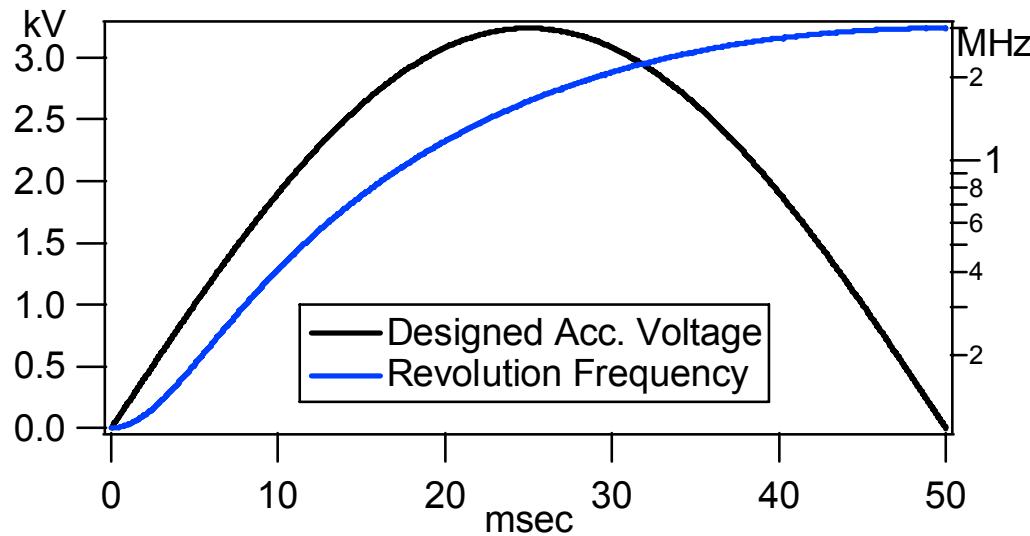


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New requirement-



Designed Acceleration voltage , Revolution Frequency Vs Time

- Long acceleration voltage pulse
- Dynamic allocation of induction acceleration cells using DSP's



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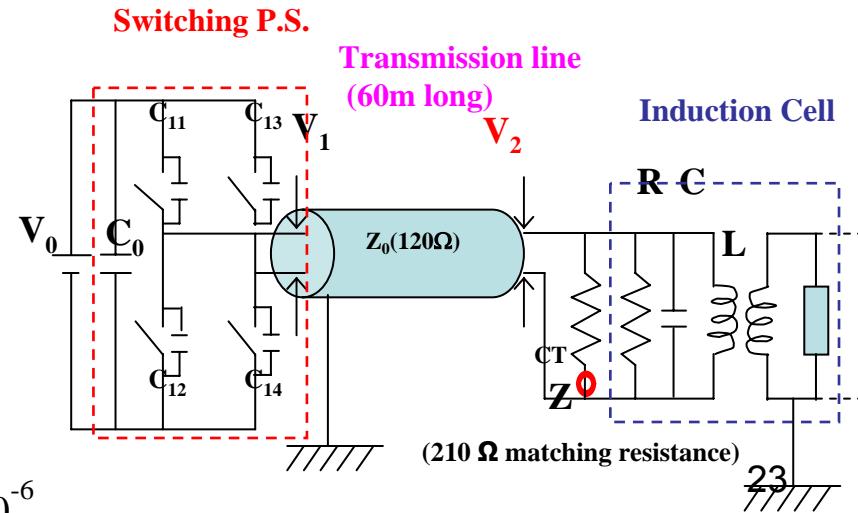
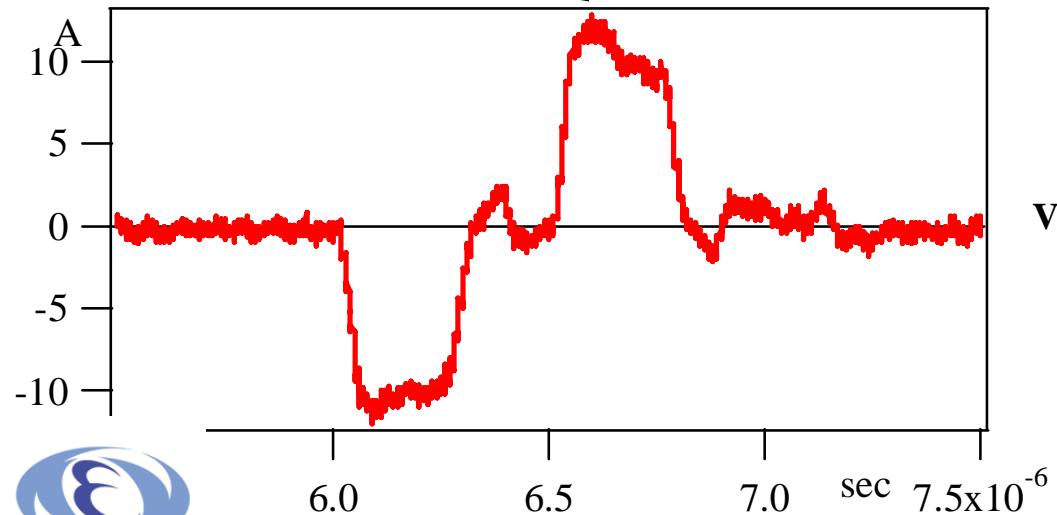
Existing Induction acceleration cell

- Maximum rep-rate of 1 MHz
- Maximum output voltage of 2 kV with a droop of 15% in 250 ns

$$droop \propto \exp(-Zt/L)$$

where Z is total impedance (Cell + Matching resistance)

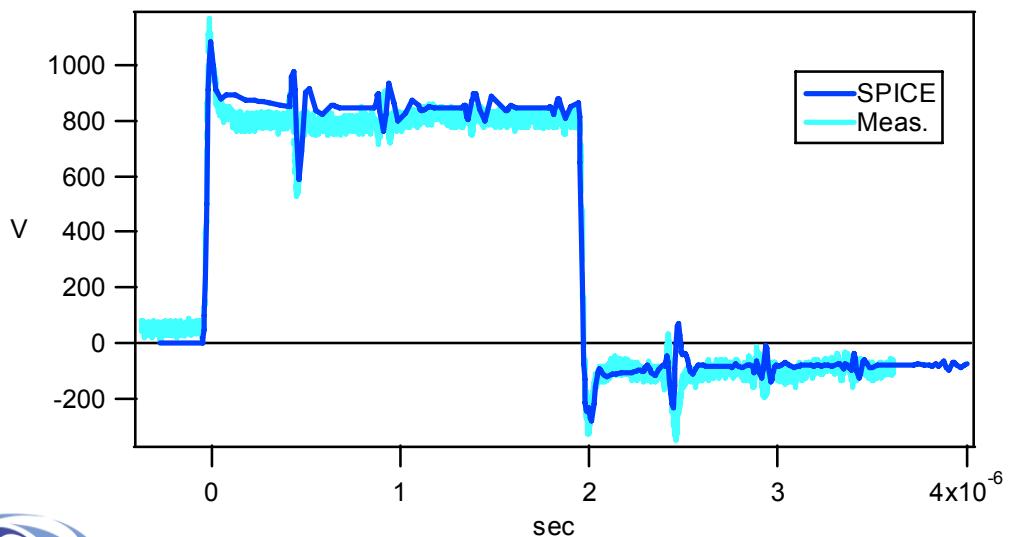
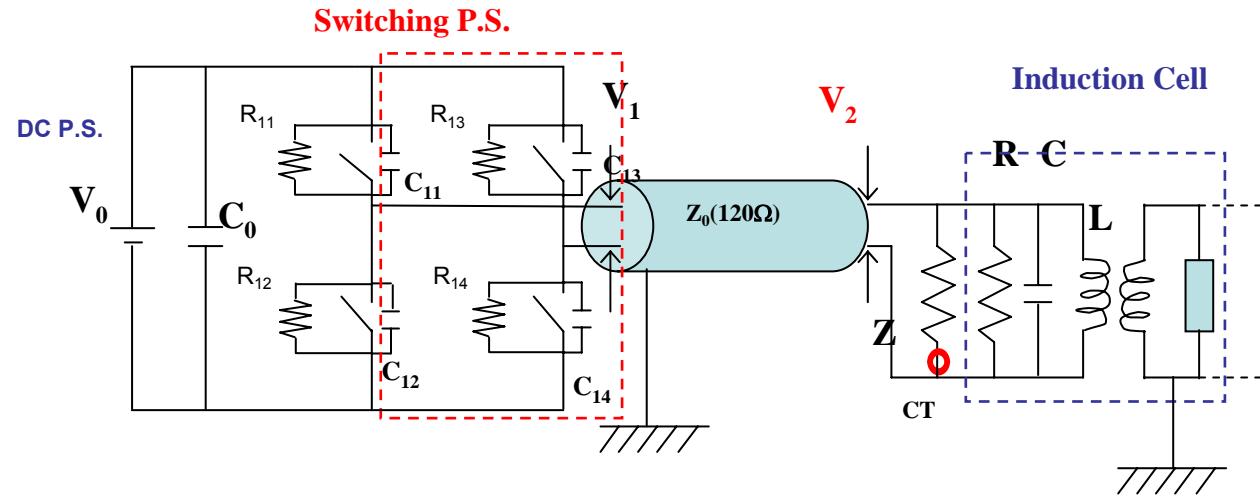
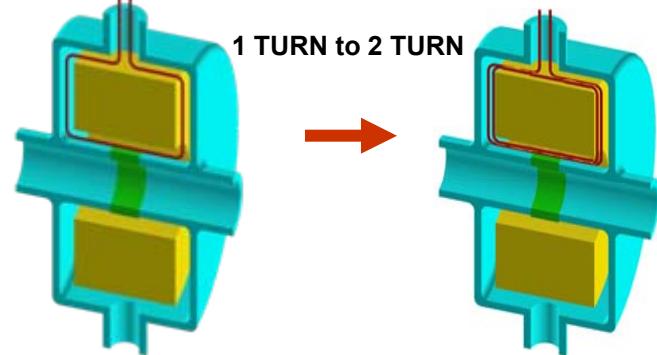
L is Inductance of Cell





SPICE SIMULATION

Equivalent circuit



Demerit -
Secondary voltage
becomes HALF
 $V_s = V_p/2$

1 turn cell

2 turn cell

$L = 110 \mu H$

$L = 440 \mu H$

$C = 260 pF$

$C = 180 pF$

$R = 330 \Omega$

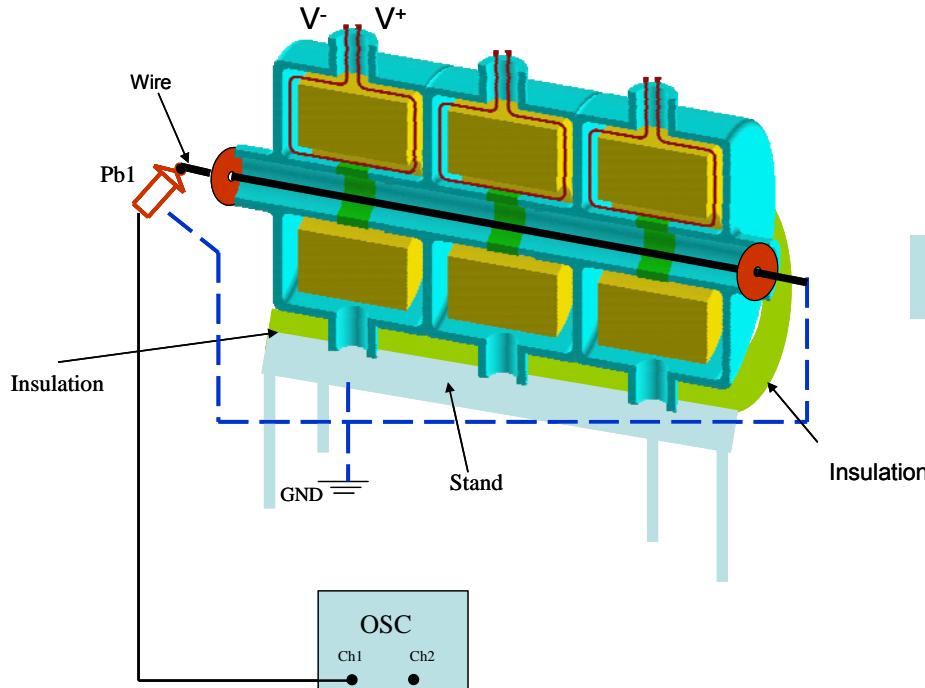
$R = 1280 \Omega$

$R_m = 220 \Omega$

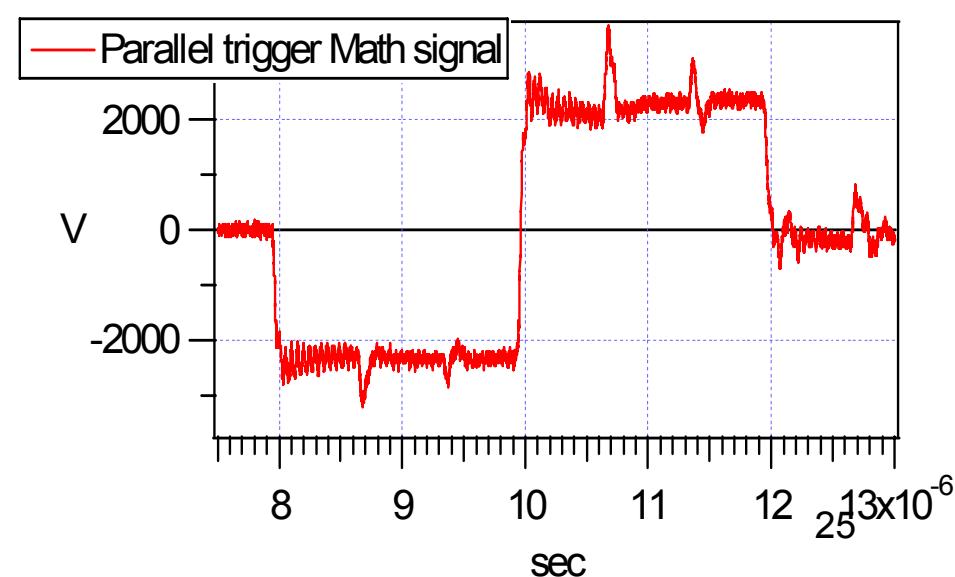
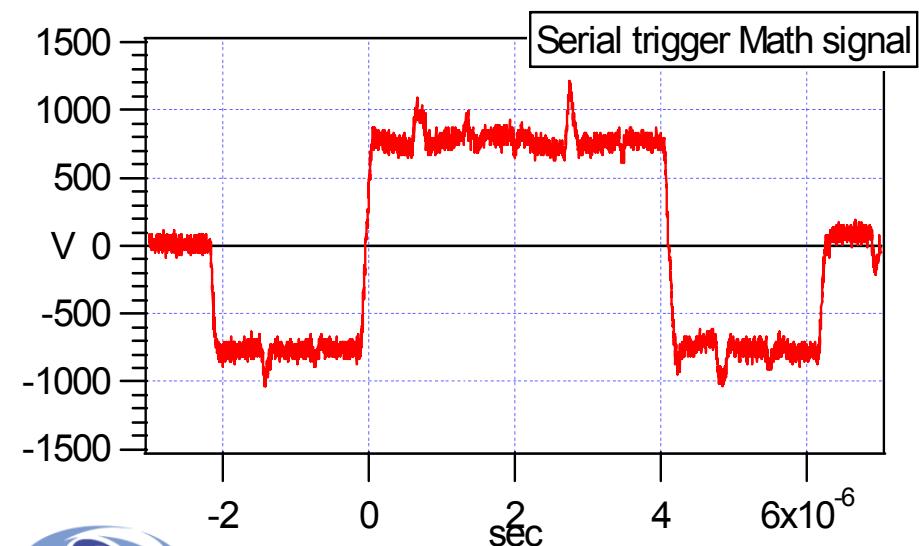
$R_m = 134 \Omega$

- Flatness due to multiple reflections
- Undershoot because of downstream circuit conditions

Wire experiment setup for 3 cells (2 turn)



Wire Measurement



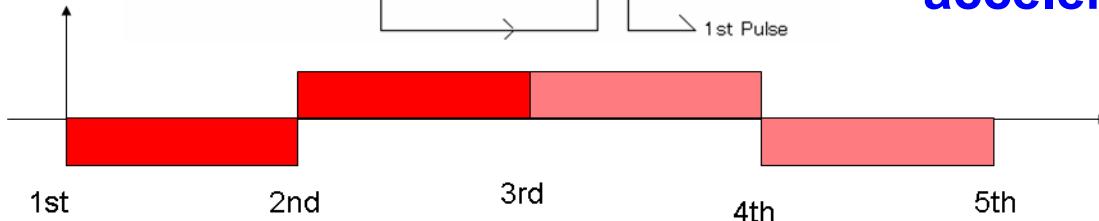
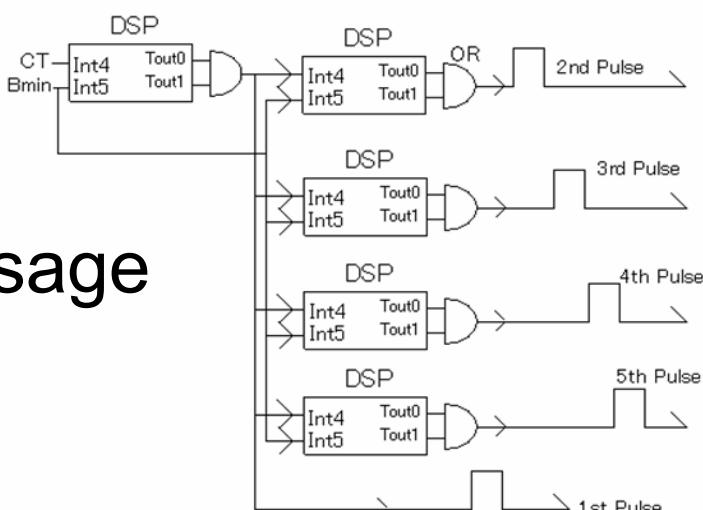
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DSP usage



5 DSP's needs to be synchronized for start and stop of generation of SET/RESET pulse of acceleration

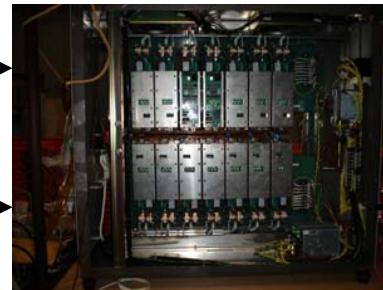
beam simulator



DSP
Gate control

Power line

Switching Power Supply



Acceleration cell

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Year	2007	08	09
Accelerator			
ECR ion source	→		
cluster ion source	→	→	
modification works			
•beam line	→		
•replacement of RF by IAS		→	→
beam commission			